

# For Disc Type Wet Extrusion Process

## 濕式擠出成型用

### Temperature Compensation Type

Designation	Electric Properties			Reference Code		Reference Firing Temperature, °C	Addition of Low Melt Additive
	K-value at 1MHz	Q Factor Min.	I.R. Min. MΩ	JIS	EIA		
NPO-10	10.0±1.0	2000	10 <sup>5</sup>	CH	COH	1320±10	-
NPO-13	13.0±1.0	3000	10 <sup>5</sup>	CG	COG	1330±10	-
NPO-20	23.0±1.0	3000	10 <sup>5</sup>	CG	COG	1330±10	-
NPO-40	44.0±1.5	3000	10 <sup>5</sup>	CG	COG	1210±10	-
NPO-110	107±3	3000	10 <sup>5</sup>	CG	COG	1270±10	O
N750	100±15	2000	10 <sup>5</sup>	UH	U2H	1230±10	-
SL-330	325±15	2000	10 <sup>5</sup>	SL	-	1355±10	O

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### High-K Type

Designation	Electric Properties			Reference Code		Reference Firing Temperature, °C	Addition of Low Melt Additive
	K-value at 25 °C	D.F. Max. %	I.R. Min. $\Omega$	JIS	EIA		
Z5U	11500±1500	1.0	10 <sup>4</sup>	ZE	Z5U	1360±10	-
Z5V	20000±3000	1.0	10 <sup>4</sup>	ZF	Z5V	1380±10	-
Y5U	8500±850	1.0	10 <sup>4</sup>	YE	Y5U	1330±10	-
Y5E	1710±100	1.0	10 <sup>4</sup>	YA	Y5E	1255±10	O
Y5P	3650±200	1.5	10 <sup>4</sup>	YB	Y5P	1390±10	O
Y5V	15500±2000	1.0	10 <sup>4</sup>	YF	Y5V	1380±10	-
Y5P-XHT	3650±350	2.0	10 <sup>4</sup>	YB	Y5P	1390±10	O
X7R	3300±330	2.0	10 <sup>4</sup>		X7R	1355±10	O

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### Semi-conductive Type

Designation	Electric Properties			Reference Code		Reference Firing Temperature, °C	Addition of Low Melt Additive
	K-value at 25°C	D.F.Max.%	I.R. Min. Ω	JIS	EIA		
SBL— Y5V	12000±10 00	0.45	10 <sup>4</sup>	YF	Y5V	1300±10	-
SBL— Y5U	8500±500	0.50	10 <sup>4</sup>	YE	Y5U	1325±10	-